Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L3	80	GAU-TSAI-SHENG-.in. LIN-BURN-J-.in. LIN-BURN-JENG-.in.	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/26 11:15
L4	66	GAU-TSAI-SHENG-.in. LIN-BURN-J-.in. LIN-BURN-JENG-.in.	US-PGPUB; USPAT	OR	ON	2005/09/26 11:19
L5	14	3 not 4	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/26 11:19
L6	833386	resist photoresist photo-sensitive photo-resist photosensitive (sensitive near (photo light energy radiation))	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/26 11:22
L7	1951612	thickness	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/26 11:22
L8	42622	topograph$5	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/26 11:22
L9	322	6 with 7 with 8	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/26 11:47
L10	43	9 with (alter$3 chang$3 produc$5)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/26 11:48
L11	15	9 with (dosage dose)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/26 11:37
L12	64	9 with (expos$4)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/26 11:41

L13	4	9 with (compensat$5)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/26 11:48
L14	54	9 with (planariz$6)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/26 11:46
L15	2934066	non-planar via trench	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/26 11:47
L16	2036	6 with 7 with 15	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/26 11:47
L17	139	16 with (alter$3 chang$3 produc$5)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/26 11:49
L18	4	16 with (compensat$5)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/26 11:48
L19	3	18 not 13	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/26 11:48
L20	45	16 with (alter$3 chang$3 produc$5 planariz$5) with (expos$5 dose dosage)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/26 11:50
L21	43	20 not (10 11 12 13 14 18)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/26 12:01
L22	2	("6064466").PN.	US-PGPUB; USPAT; EPO; JPO; DERWENT	OR	OFF	2005/09/26 14:21

L25	10	6 near3 7 near3 measur$5 near3 (profilometry interferometry (scanning adj electron adj microscope))	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/26 14:26
L28	31	6 near3 expo$3 near3 (((mirror proximity) near2 alignment) (step near (stitch repeat)))	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/26 14:31
L29	3	6 with expo$3 with (((mirror proximity) near2 alignment) (step near (stitch repeat))) with conventional$2	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/26 14:37
L32	11	6 with plug with etchback	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/26 14:42
L33	176	6 with plug with (etch$3 adj back etch$3-back)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/26 14:42
L34	4	6 with plug with (etch$3 adj back etch$3-back) with conventional$3	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/26 14:43